

STEM-EELS Studies of the Local Structure and Coordination of Al₂O₃/Si interfaces in Si Solar Cells

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The efficiency of the Si solar cells may be significantly improved by coating of aluminum oxide (Al₂O₃) on Si surfaces for surface passivation[1]. Recent studies show that the efficiency is largely governed by the nature of the interface between Al₂O₃ and Si layer, which can be changed *via* post-annealing process[2]. Due to the limited thickness of Al₂O₃/Si interface, of only one or two nanometers, measurements by general methods such as x-ray photoelectron spectroscopy[3] and secondary ion mass spectrometry[4], can hardly provide detailed information on this interface. In the present work, the microstructure and chemical bonding of interfaces in Si/Al₂O₃ and their change with annealing were investigated by high-resolution scanning transmission electron microscopy (STEM) imaging and electron energy-loss spectroscopy (EELS), at sub-nm resolution. The local coordination of Al and Si at the interface was determined by energy-loss near-edge structure (ELNES) of EELS spectra.

Amorphous Al₂O₃ passivation on Si (001) film was fabricated *via* a novel atmospheric pressure chemical vapor deposition (APCVD) process and activated by annealing at different temperatures. Annular dark-field (ADF), atomic Z-contrast images and EELS spectra were recorded from as-deposited and annealed samples in a JEOL 2100F microscope operated at 200 KV. A focused probe with full-width at half-maxima (FWHM) of 0.26 nm was used to obtain ADF, atomic z-contrast images and Si L-edge and Al L-edge EELS spectra across the Al₂O₃/Si interface. The energy resolution of EELS spectra is about 1.2 eV. The background in EELS spectra was subtracted by using the power-law model[5].

Figure 1 shows the cross-sectional annular dark-field (ADF) images of the as-deposited and annealed (at 500 °C) Al₂O₃/Si samples. An interfacial layer exists at the Al₂O₃/Si interface in both samples. The thicknesses of Al₂O₃ and interfacial layers were measured to be 21.8±0.4 nm and 1.5±0.2 nm for as-deposited sample. After post-annealing, the thickness Al₂O₃ of film decreased slightly (19.5±0.7 nm), and interfacial layer becomes thicker (2.3±0.4 nm). Beyond the crystalline Si layer, no lattice structure is visible, indicating that the interfacial and Al₂O₃ layers are amorphous before and after annealing.

EELS spectra of Si and Al L-edges acquired from the two samples, across the Al₂O₃/Si interfaces are given in Fig. 2. Clear differences of the spectra were observed in the interfacial regions (red curves). In the as-deposited samples, Si is in the elemental state, as evidenced by Si L₋₂₃ edge located at 100 eV. And only octahedral peak from AlO₆ exists in the amorphous alumina layer (marked as octahedral peak O). However, after annealing at 500 °C, in addition to the octahedral peak at 80 eV, there is a new peak at 78 eV (labeled as T), indicating the formation of tetrahedral Al₂O₄ in the Al₂O₃ layer. Also the tetrahedral configuration of SiO₄ emerges across the whole interface, as evidenced by intense Si L₋₂₃ edge at about 105 eV.

Bulk properties of the samples, such as surface defect density (D_{it}) and fixed negative charge (Q_f), were also measured from the same samples. The results from detailed STEM-EELS

studies, with a correlation with bulk measurements will be presented. The impact of post-annealing on structural properties of the Al₂O₃/Si interface and efficiency of the Si solar cell will be discussed.

References:

[1] L.E. Black, K.R. McIntosh, Applied Physics Letters **100** (2012), p 202107.
 [2] J. Benick, et al., Photovoltaic Specialists Conference (PVSC) (2010) p. 000891.
 [3] V. Naumann, et al., Journal of Vacuum Science & Technology A **30** (2012), p 04D106.
 [4] L. Gosset, et al., Journal of non-crystalline solids **303** (2002), p 17.
 [5] R.F. Egerton in "Electron energy-loss spectroscopy in the electron microscope", ed. R.F. Egerton, (Springer, New York) p.269.

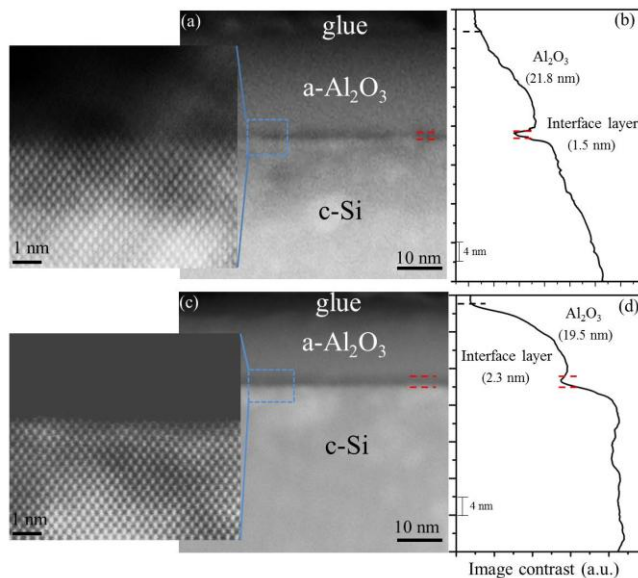


Figure 1. (a, c) Cross sectional ADF images of as-deposited samples (upper) and the sample annealed at 500 °C (lower) along the [011] direction and STEM images from the interface area (inset), (b, d) the profiles of the image contrast.

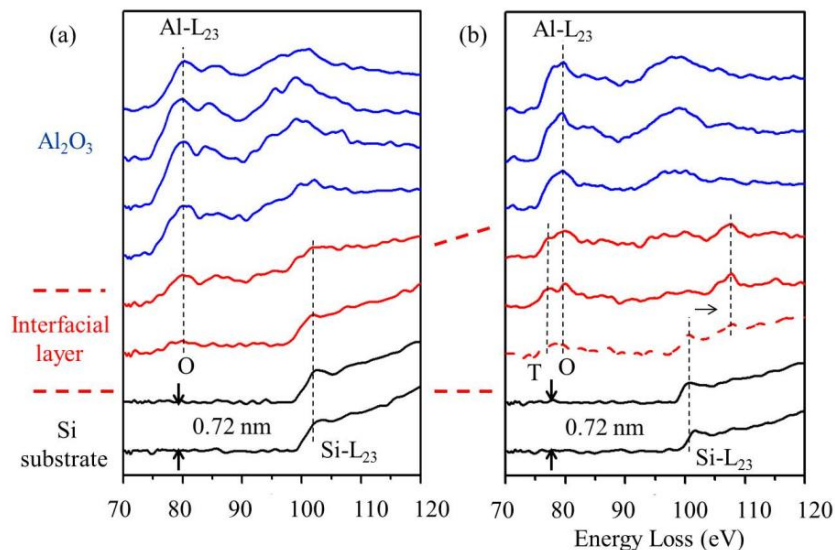


Figure 2. EELS spectra before (a) and after annealing at 500 °C (b).